

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

del Puerto *et al.*

Appl. No. (to be assigned)

Filed: (herewith)

For: **Wafer Handling System and
Method for Use in Lithography
Patterning**

Confirmation No. (to be assigned)

Art Unit: (to be assigned)

Examiner: (to be assigned)

Atty. Docket: 1857.0290000

**Authorization to Treat a Reply as Incorporating an Extension of Time
under 37 C.F.R. § 1.136(a)(3)**

Commissioner for Patents
Washington, D.C. 20231

Sir:

The U.S. Patent and Trademark Office is hereby authorized to treat any concurrent or future reply that requires a petition for an extension of time under this paragraph for its timely submission, as incorporating a petition for extension of time for the appropriate length of time. The U.S. Patent and Trademark Office is hereby authorized to charge all required extension of time fees to our Deposit Account No. 19-0036, if such fees are not otherwise provided for in such reply. A duplicate copy of this authorization is enclosed.

Respectfully submitted,

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